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(12) **United States Design Patent**
Yoshida et al.

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(54) **BOAT FOR SUBSTRATE PROCESSING APPARATUS**

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(**) Term: **14 Years**

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(30) **Foreign Application Priority Data**

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(52) **U.S. Cl.**
USPC **D13/182**

(58) **Field of Classification Search**
USPC D13/182; D15/144, 144.1, 199; 118/715, 500, 728, 729; 211/41.18; 432/253, 258; 156/345.51, 345.52, 156/345.53, 345.55; 414/217, 220.01, 414/935–941
CPC C23C 16/458; C23C 16/4581; C23C 16/4582; C23C 16/4583; C23C 16/4584; C23C 16/4586; C23C 16/4587; C23C 16/4588; C30B 31/14; H01L 21/673; H01L 21/67303; H01L 21/67306; H01L 21/67309; H01L 21/67313; H01L 21/67316; H01L 21/67323; H01L 21/67326; H01L 21/6733
See application file for complete search history.

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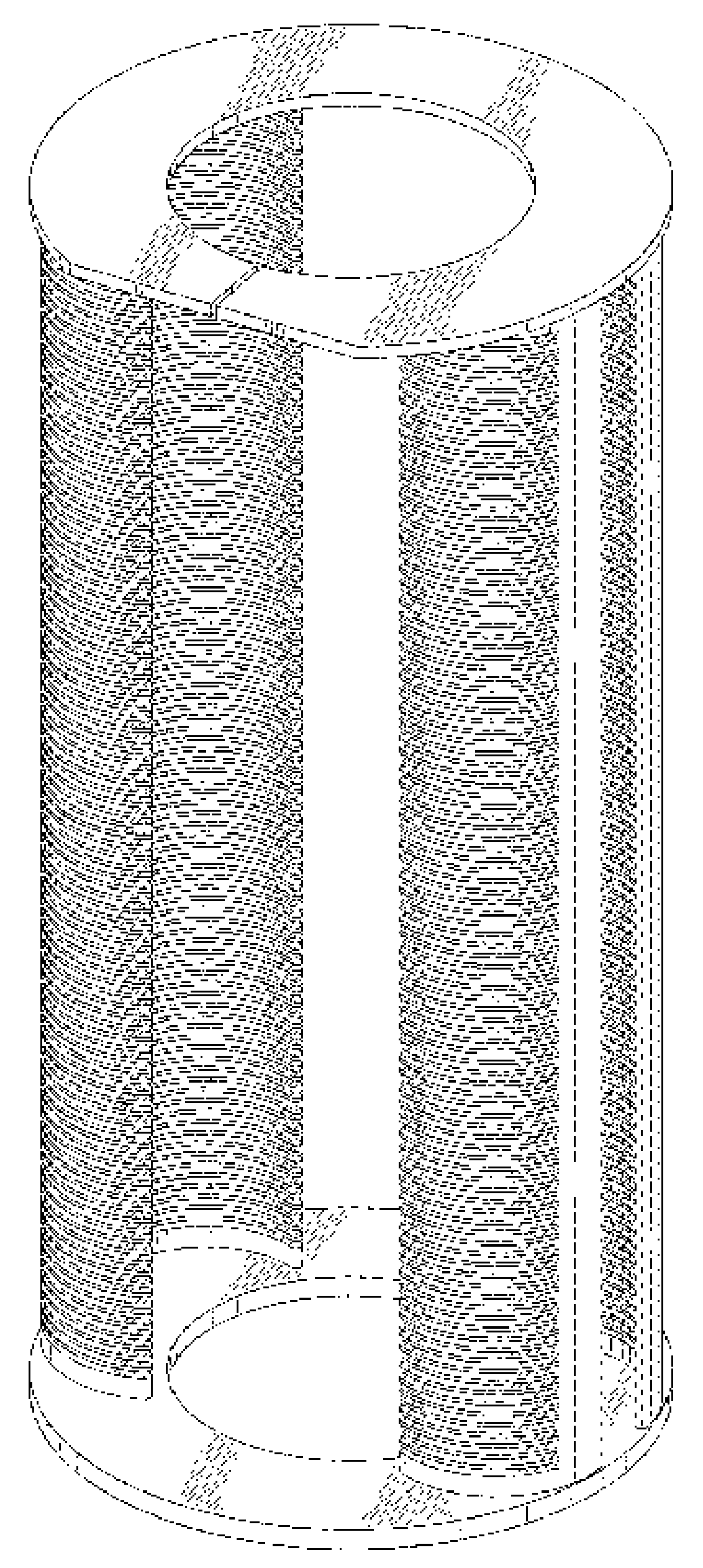
(57) **CLAIM**

The ornamental design for a boat for substrate processing apparatus, as shown and described.

DESCRIPTION

FIG. **1** is a front, top and right side perspective view of a boat for substrate processing apparatus showing our new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a rear elevational view thereof;
FIG. **4** is a left side elevational view thereof;
FIG. **5** is a right side elevational view thereof;
FIG. **6** is a top plan view thereof;
FIG. **7** is a bottom plan view thereof;
FIG. **8** is a cross sectional view taken along line **8-8** in FIG. **2**; and,
FIG. **9** is a cross sectional view taken along line **9-9** in FIG. **2**.

1 Claim, 8 Drawing Sheets



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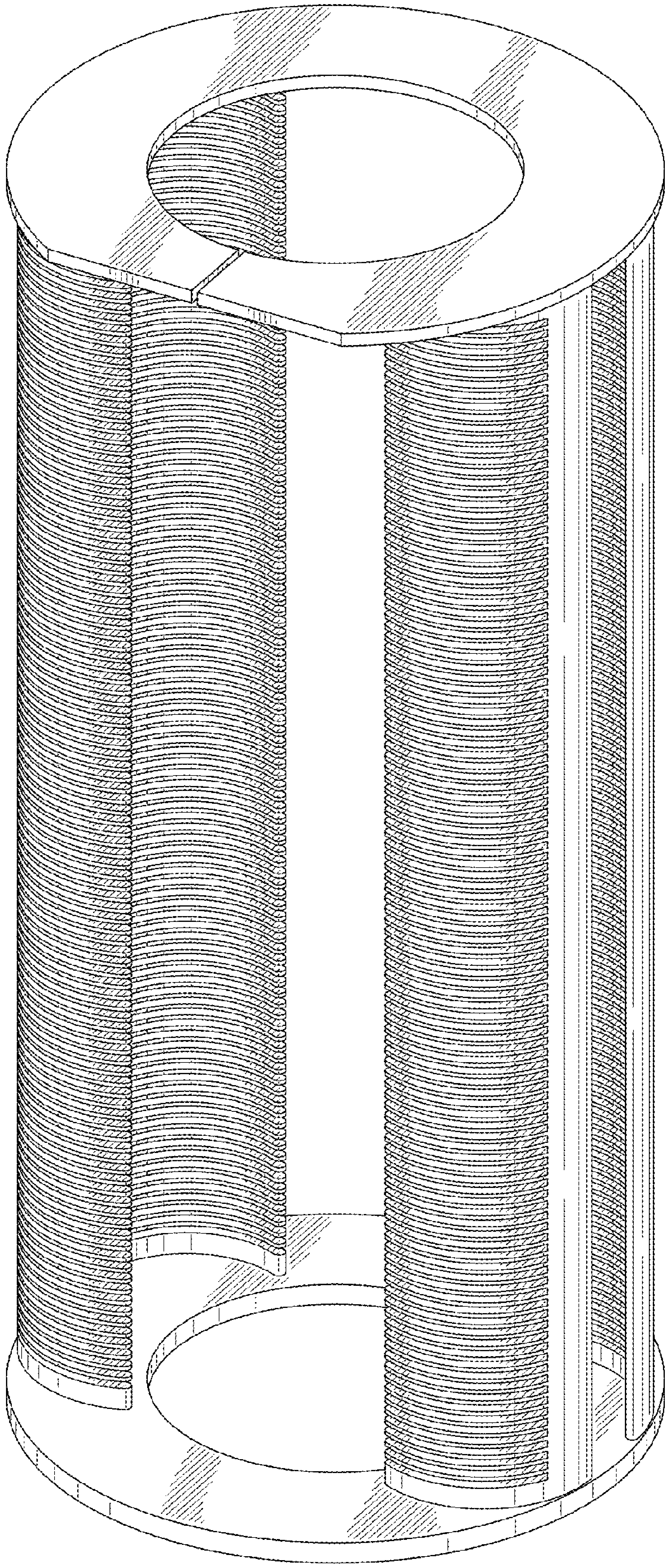

FIG. 1

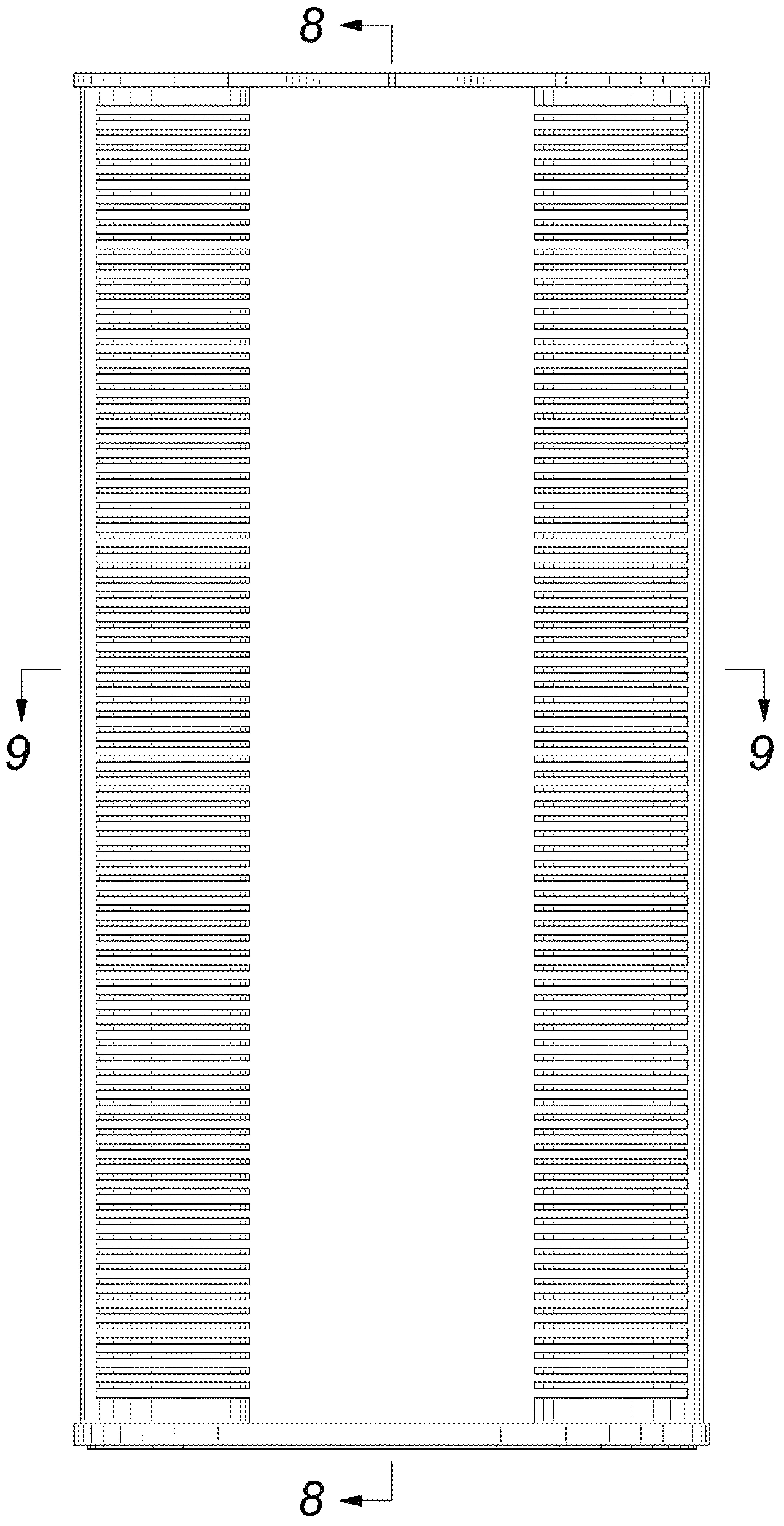

FIG. 2

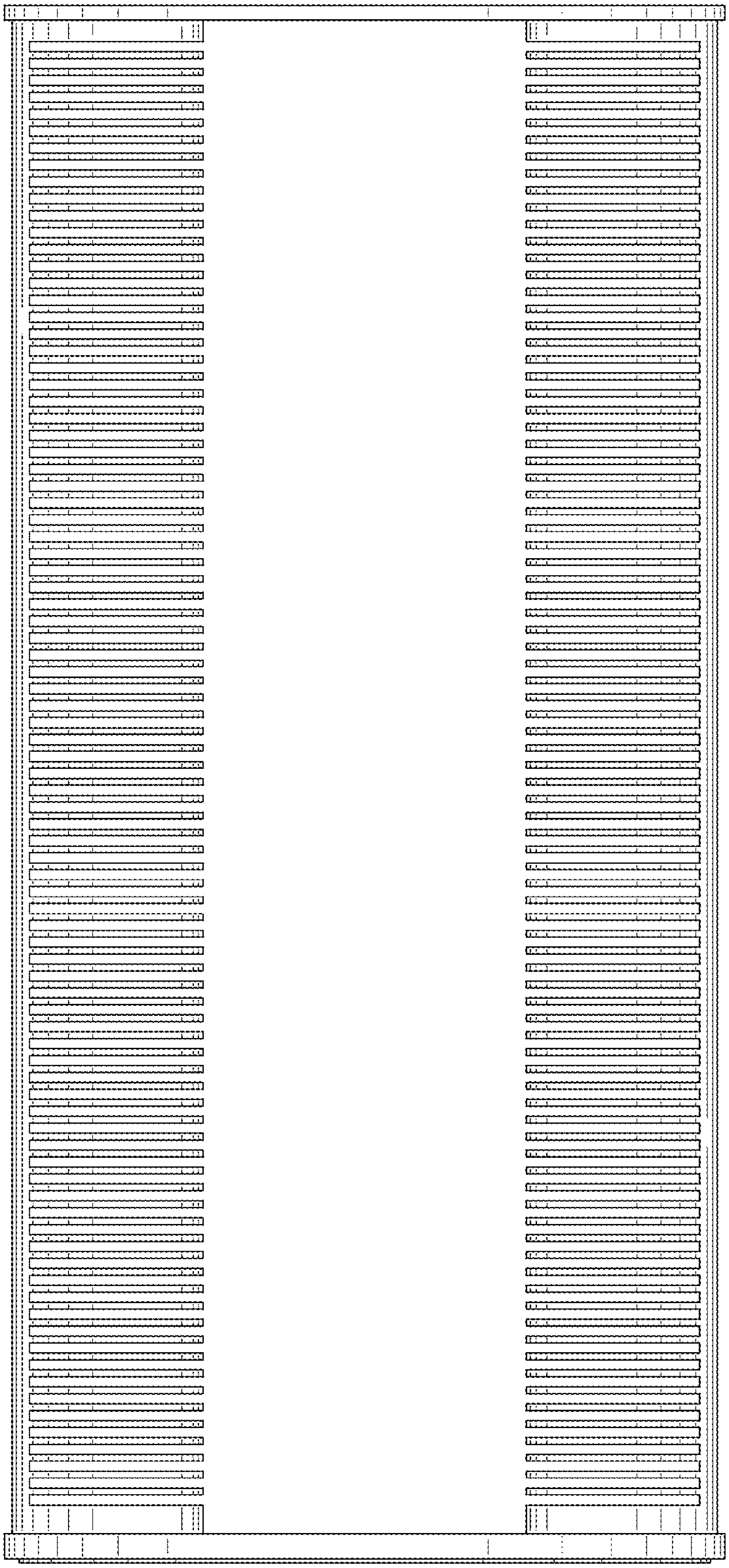

FIG. 3

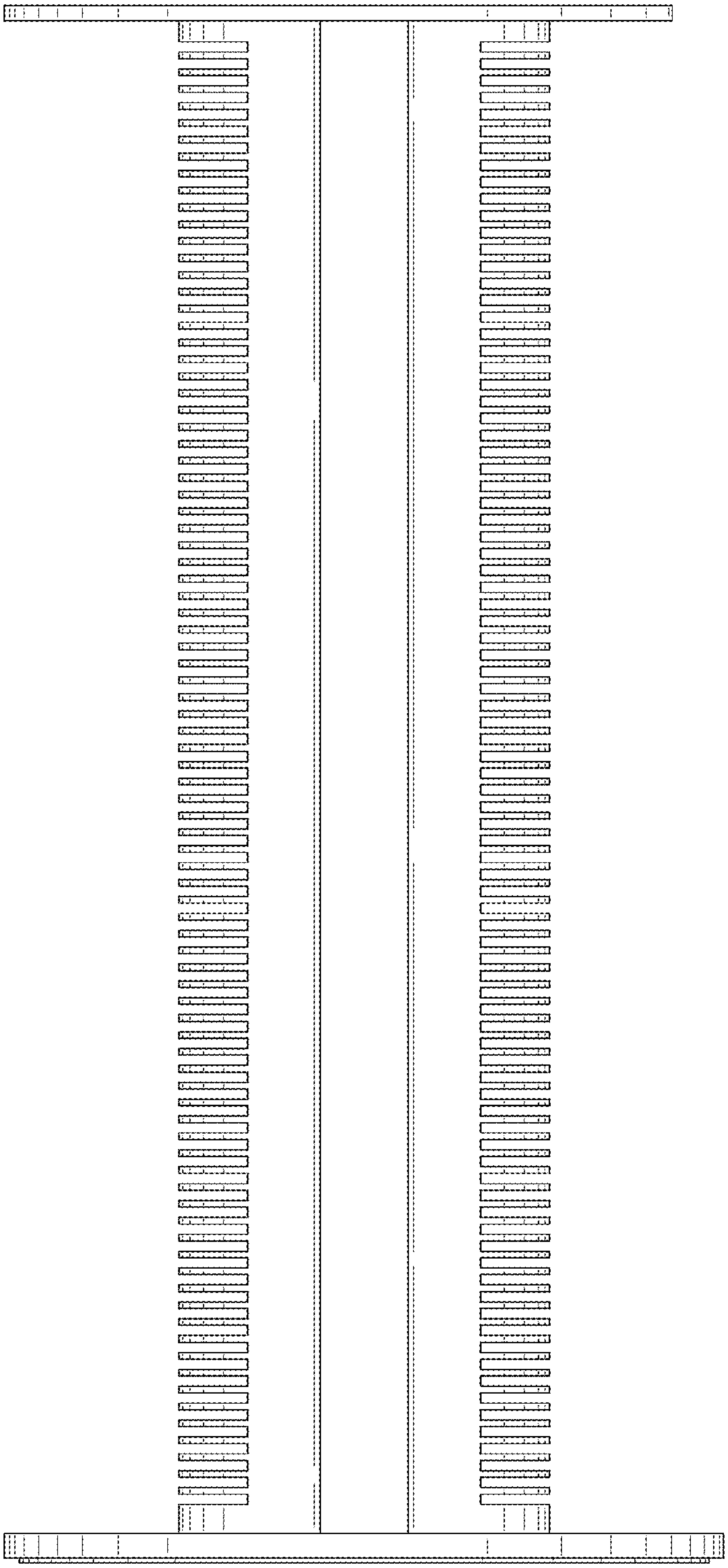

FIG. 4

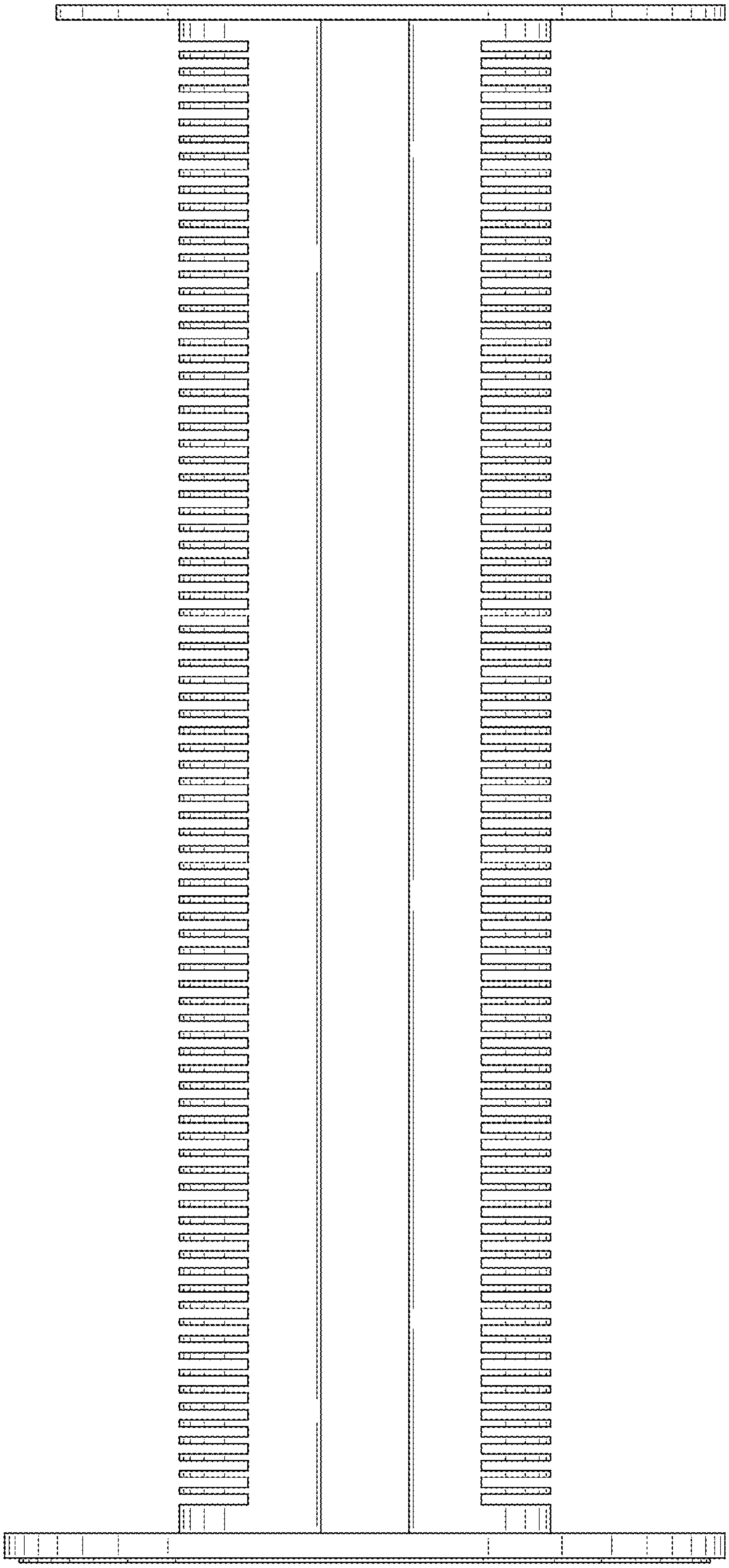

FIG. 5

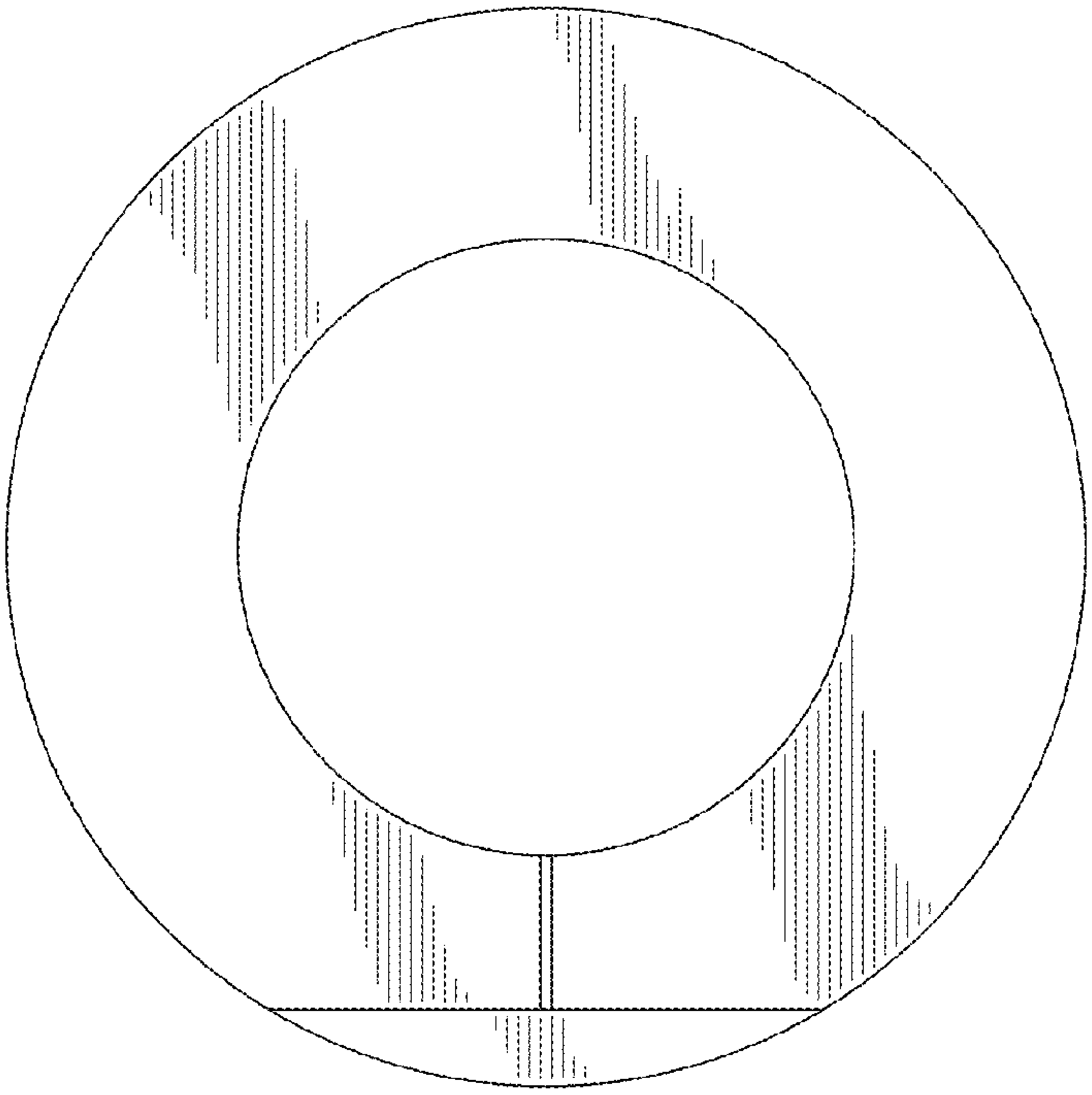

FIG. 6

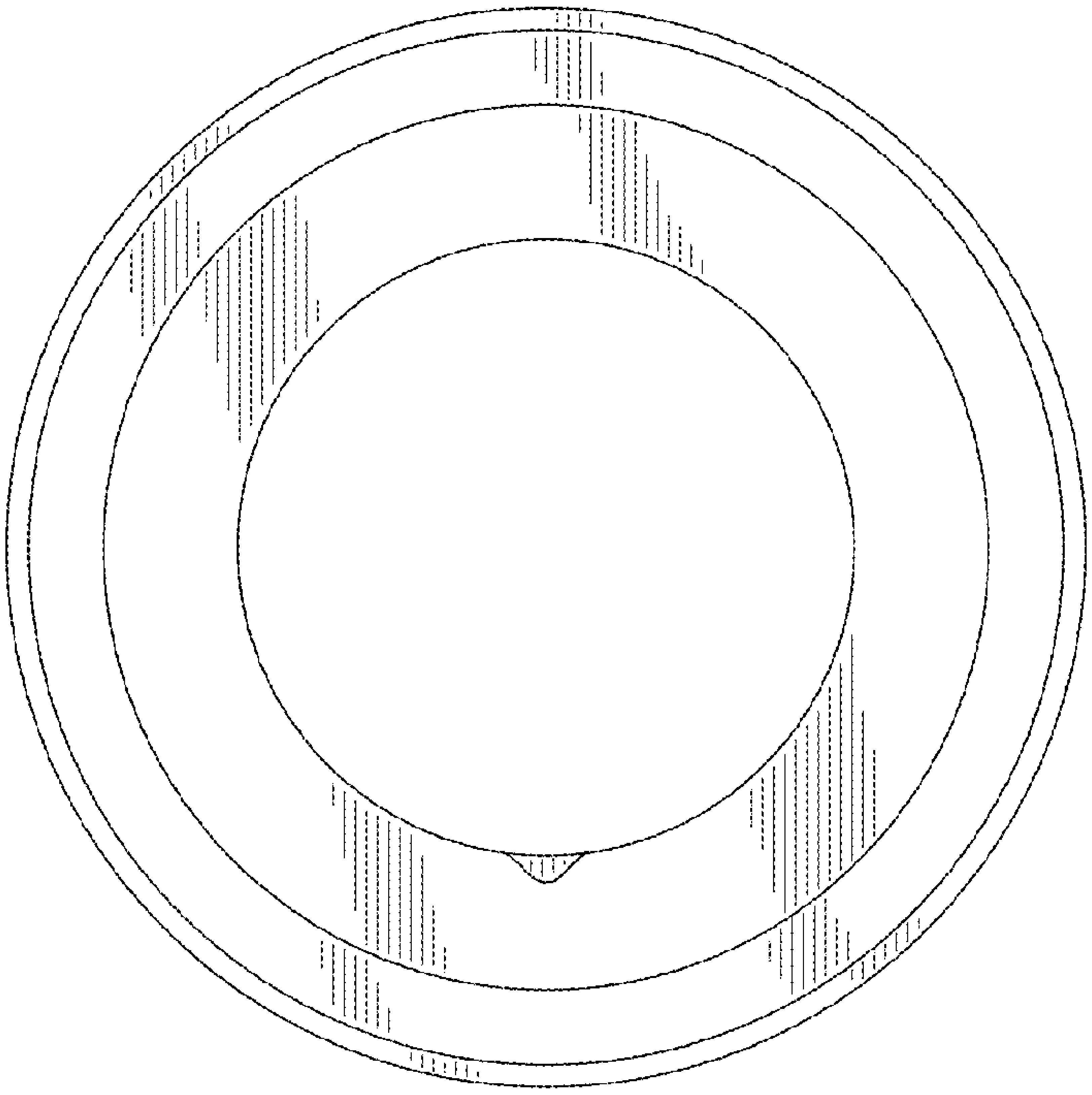

FIG. 7

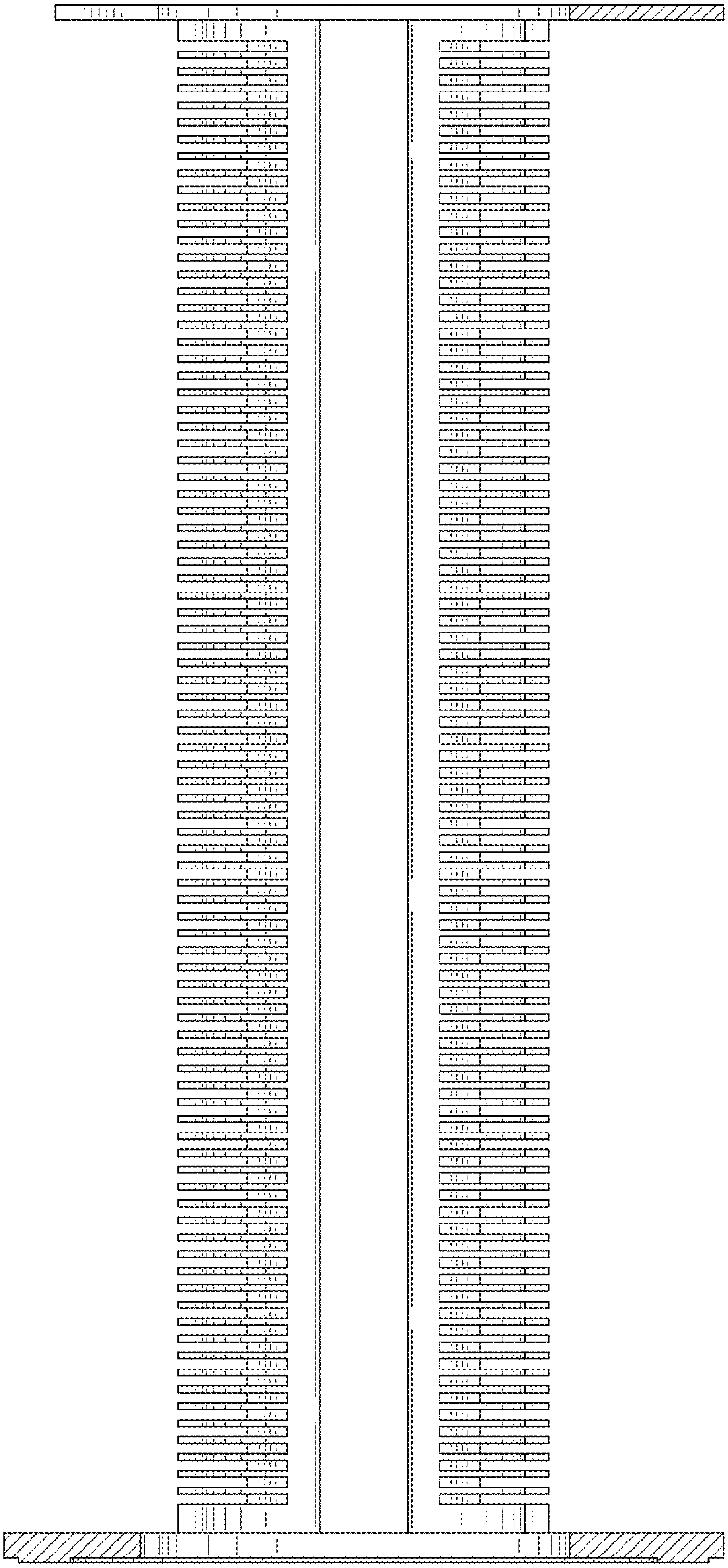

FIG. 8

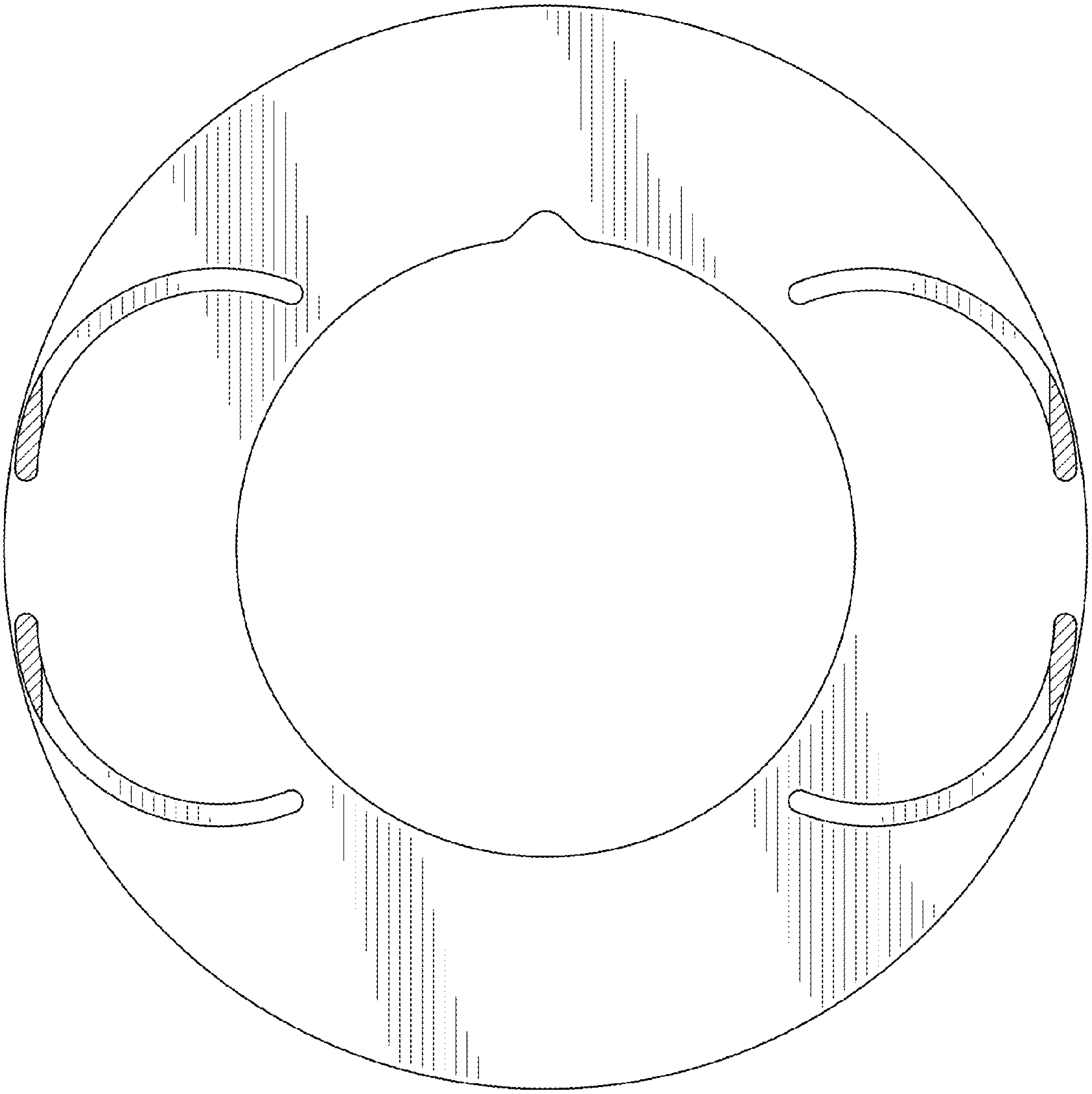

FIG. 9